



Applicants:

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Assignee:

Nanometrics Incorporated

Title:

Apparatus And Method For The Measurement Of Diffracting Structures

Serial No.:

09/670,000

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Unknown

Group Art Unit:

2878

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San Jose, California February 27, 2002

COMMISSIONER FOR PATENTS Washington, D. C. 20231

## SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT **UNDER 37 CFR § 1.97(b)**

Dear Sir:

Pursuant to 37 C.F.R. § 1.56, § 1.97 and § 1.98, the documents listed on the accompanying PTO Form-1449 are called to the attention of the Examiner for the above patent application. Copies of these documents are enclosed.

Citation of these documents shall not be construed as:

- an admission that the documents are necessarily prior art with respect to the 1. instant invention;
  - a representation that a search has been made; or 2.
- 3. an admission that the information cited herein is, or is considered to be, material to patentability as defined in § 1.56(b).

I hereby certify that this correspondence is being deposited with the United States Postal Service as First Class Mail in an envelope addressed to: Commissioner for Patents, Washington, D.C. 20231, on February 27, 2002

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Respectfully submitted.

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